

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)	
	:	Examiner: Alexander Markoff
MASAAKI SUZUKI)	
	:	Group Art Unit: 1746
Div. of Appln. No.: 09/695,925)	
	:	
Filed: Herewith)	
	:	
For: METHOD OF CLEANING SUBSTRATE)	July 29, 2003

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Sir:

In compliance with the duty of disclosure under 37 C.F.R. § 1.56 and in accordance with the practice under 37 C.F.R. §§ 1.97 and 1.98, the Examiner's attention is directed to the documents listed on the enclosed Form PTO-1449. Copies of the listed documents are also enclosed.

The present application is a division of co-pending Application No. 09/695,925. This Information Disclosure Statement is filed to make of record all prior art citations found in the parent and all references Applicants deem relevant to the patentability of the presently claimed subject matter.

The concise explanation of relevance for the non-English documents can be

found in the specification, in their respective English language abstracts and in a corresponding English translation.

CONCLUSION

It is respectfully requested that the above information be considered by the Examiner and that a copy of the enclosed Form PTO-1449 be returned indicating that such information has been considered.

Applicants' undersigned attorney may be reached in our New York office by telephone at (212) 218-2100. All correspondence should continue to be directed to our below listed address.

Respectfully submitted,



Attorney for Applicants
Registration No. 42,667

FITZPATRICK, CELLA, HARPER & SCINTO
30 Rockefeller Plaza
New York, New York 10112-3801
Facsimile: (212) 218-2200

Docketing

Client Matter No.: 00684.001674.5

Source of IDS Information

The attached Information Disclosure Statement:

☐ Cites information forwarded in correspondence from the client dated ____
_____.

☐ Cites information from our in-house inventor search.

☒ Other (provide brief explanation).

References cited in parent.

FORM PTO 1449 (modified) U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE LIST OF REFERENCES CITED BY APPLICANT(S) (Use several sheets if necessary)				ATTY DOCKET NO. 00684.001674.5		APPLICATION NO. Div. of 09/695,925	
				APPLICANT Masaaki Suzuki			
				FILING DATE Herewith		GROUP 1746	

U.S. PATENT DOCUMENTS							
*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
		4,341,592	7/27/82	Shortes et al.	134	2	
		5,198,634	3/30/93	Mattson et al.	219	121	
		5,747,387	5/5/98	Koizumi et al.	438	708	
		5,078,832	1/7/92	Tanaka	134	1	
		5,372,651	12/13/94	Kodama	134	26	
		5,094,898	3/10/92	Morita et al.	428	64	
		5,215,592	6/1/93	Jackson	134	1	
		4,028,135	6/7/77	Vig et al.	134	1	
		5,068,040	11/26/91	Jackson	210	748	
		4,715,392	12/29/87	Abe et al.	134	62	
		5,158,100	10/27/92	Tanaka et al.	134	105	
		5,150,239	9/22/92	Watanabe et al.	359	80	

FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES/NO/ OR ABSTRACT
		02-000315	1/5/90	Japan			abstract
		63-271938	11/9/88	Japan			yes

OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)	
	K.A. Valiev, et al., "Interactions of Short-Wave UV Radiation on Thin Layers of Organic Compounds", <i>Mikroelektronika</i> , vol. 17, no. 6, pp. 522-527 (1988) with abstract.
	J.R. Vig., "UV/Ozone Cleaning of Surfaces", <i>J. Vac. Sci. Technol.</i> , vol. A3, no. 3, Part 1, pp. 1027-1034 (1985).
	McGraw-Hill Encyclopedia of Physics, S.P. Parker, ed., p. 1135 (1983).
	L. Zafonte, et al., "UV/Ozone Cleaning for Organics Removal on Silicon Wafers", <i>SPIE vol. 470 Optical Microlithography III: Technology for the Next Decade</i> , pp. 164-175 (1984).

EXAMINER	DATE CONSIDERED
----------	-----------------

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

